



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Patent Application of)
Shunpei YAMAZAKI)
Serial No. 09/327,469)
Filed: June 8, 1999)
For: SEMICONDUCTOR DEVICE)
AND METHOD OF)
MANUFACTURING THE SAME)

Art Unit: 2814
Examiner: G. Peralta

CERTIFICATE OF MAILING

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Adeline M. Stamp

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Official Action dated January 29, 2003, please amend the
above-identified application as follows:

IN THE CLAIMS:

Please amend claims 2, 3, 20 and 21 as follows:

2. (Amended) A method of manufacturing a semiconductor device,
comprising:

a first step of forming a semiconductor film over a substrate;

a second step of holding a catalytic element that promotes the
crystallization of said semiconductor film in contact with an entire surface of said
semiconductor film;

a third step of irradiating a laser beam shaped in a rectangle or a square
while moving the laser beam from one side of said semiconductor film toward another
side thereof to sequentially crystallize said semiconductor film to form a crystalline
semiconductor film;

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